

FIG. 1

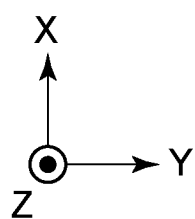
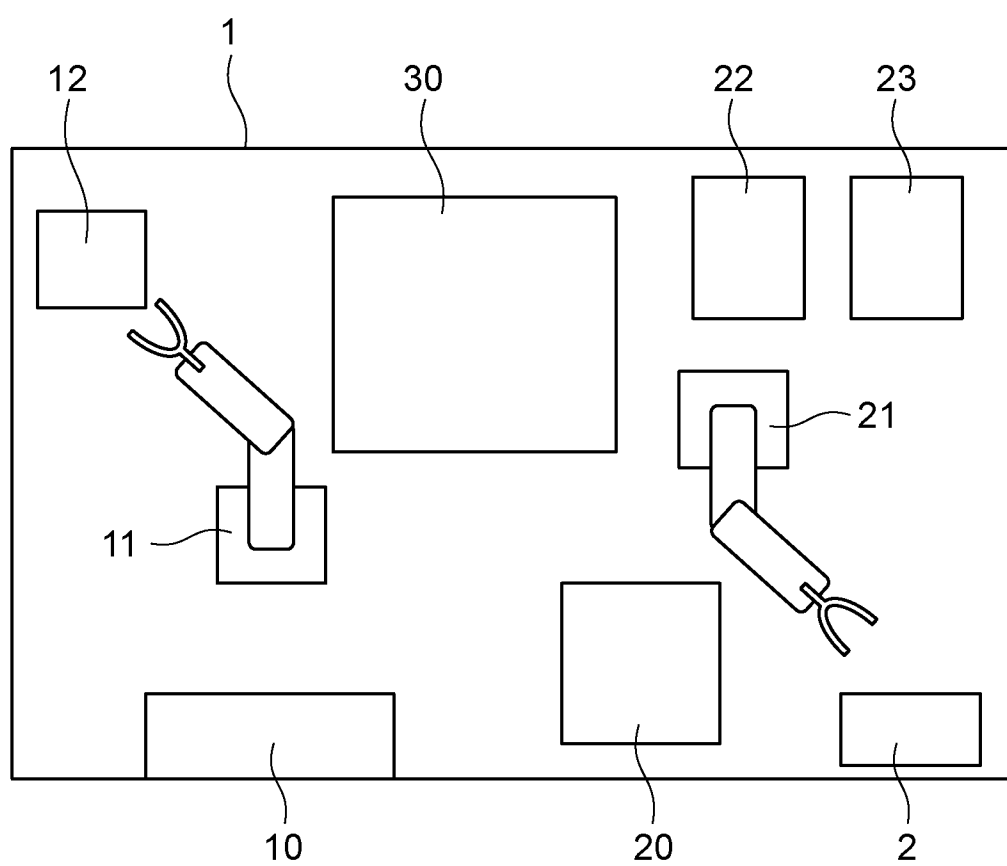


FIG. 2

30

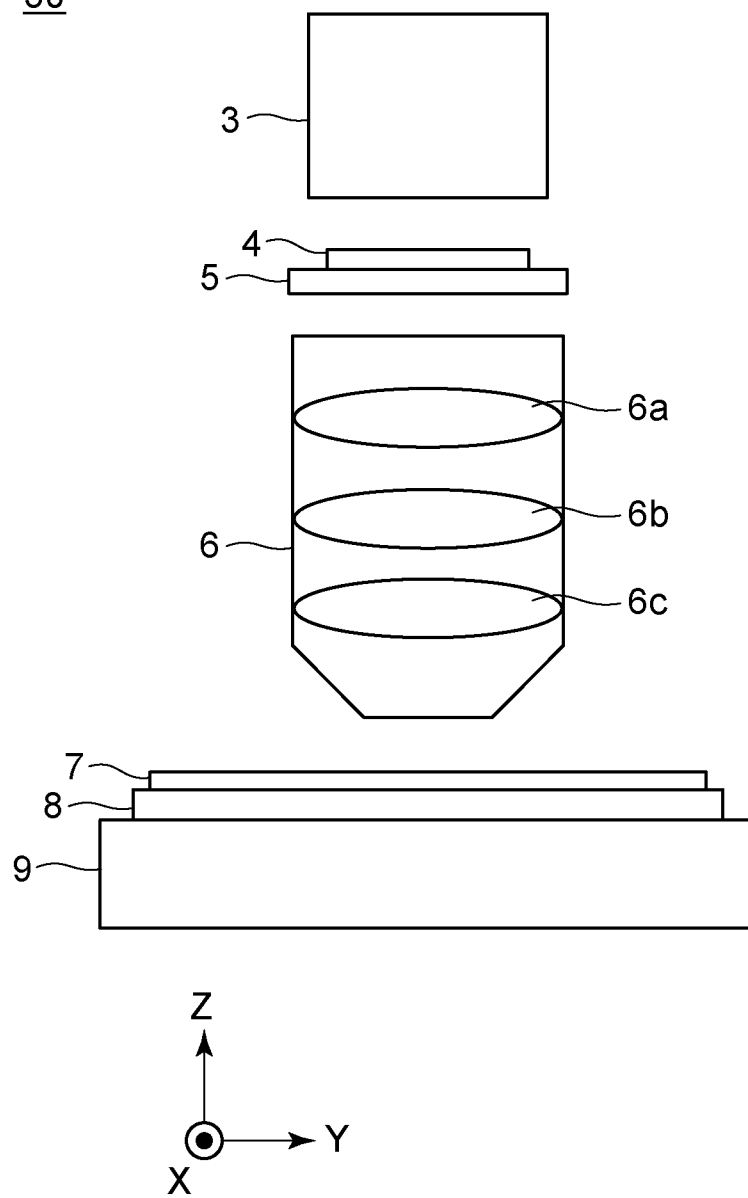


FIG. 3A

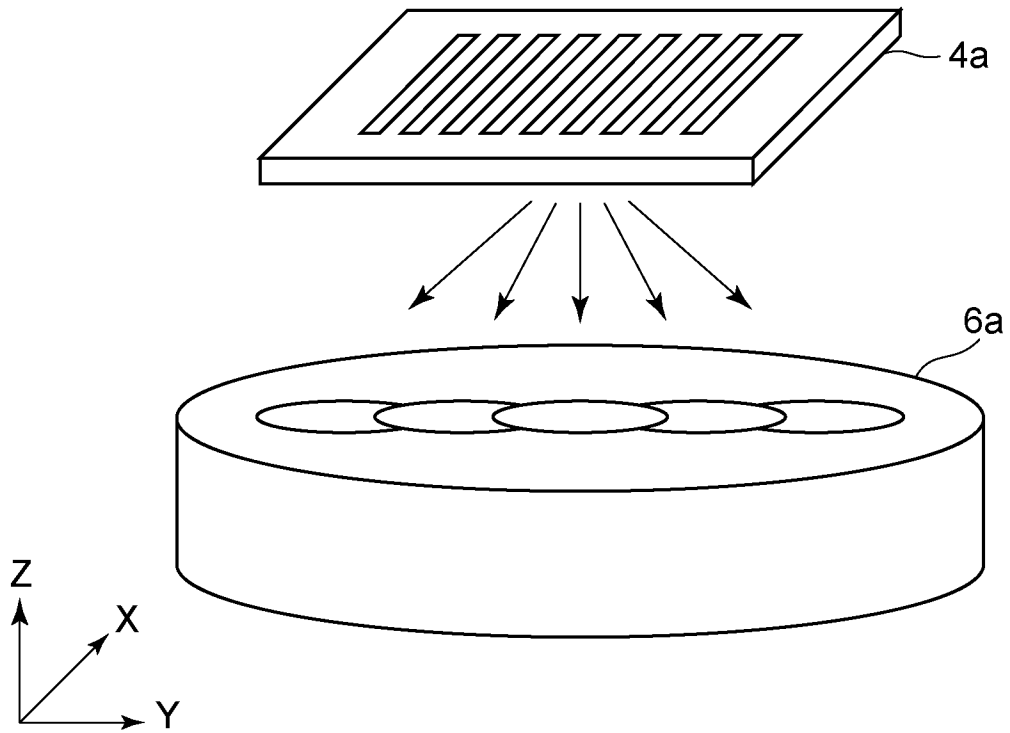


FIG. 3B

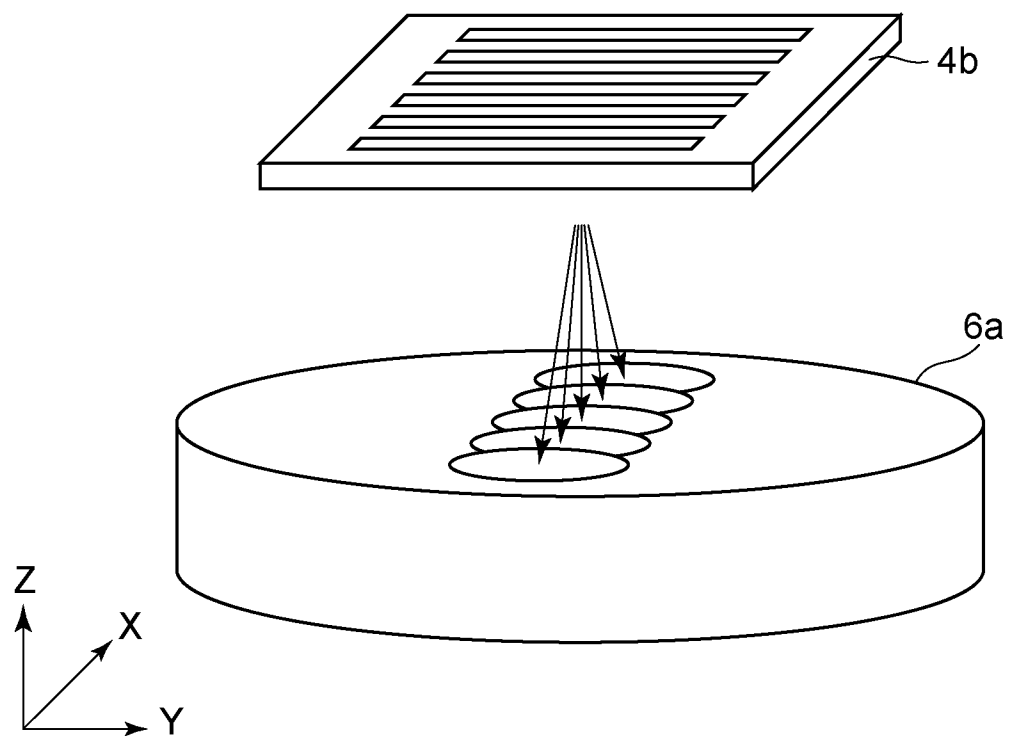


FIG. 4

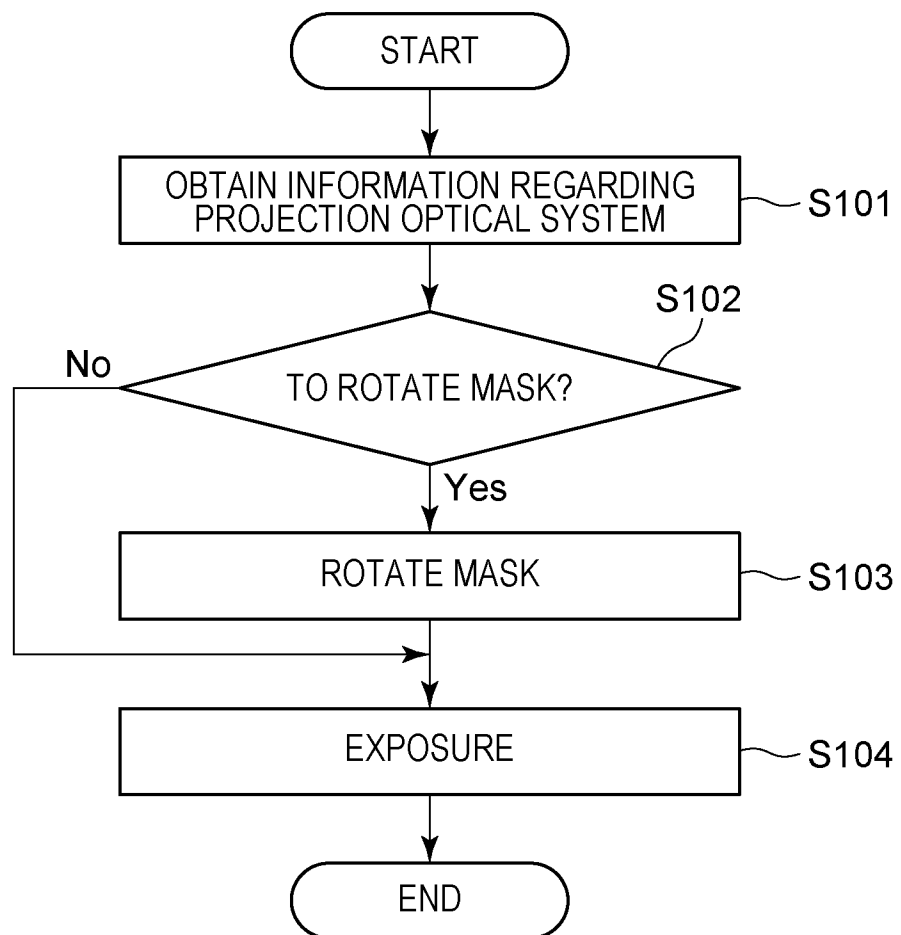


FIG. 5A

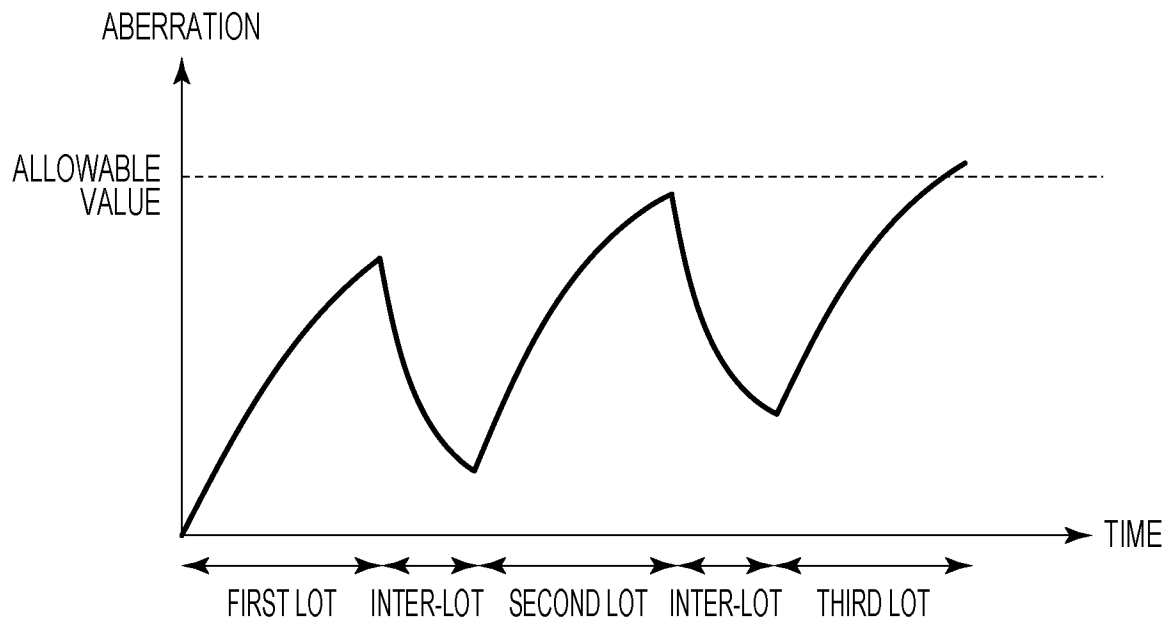


FIG. 5B

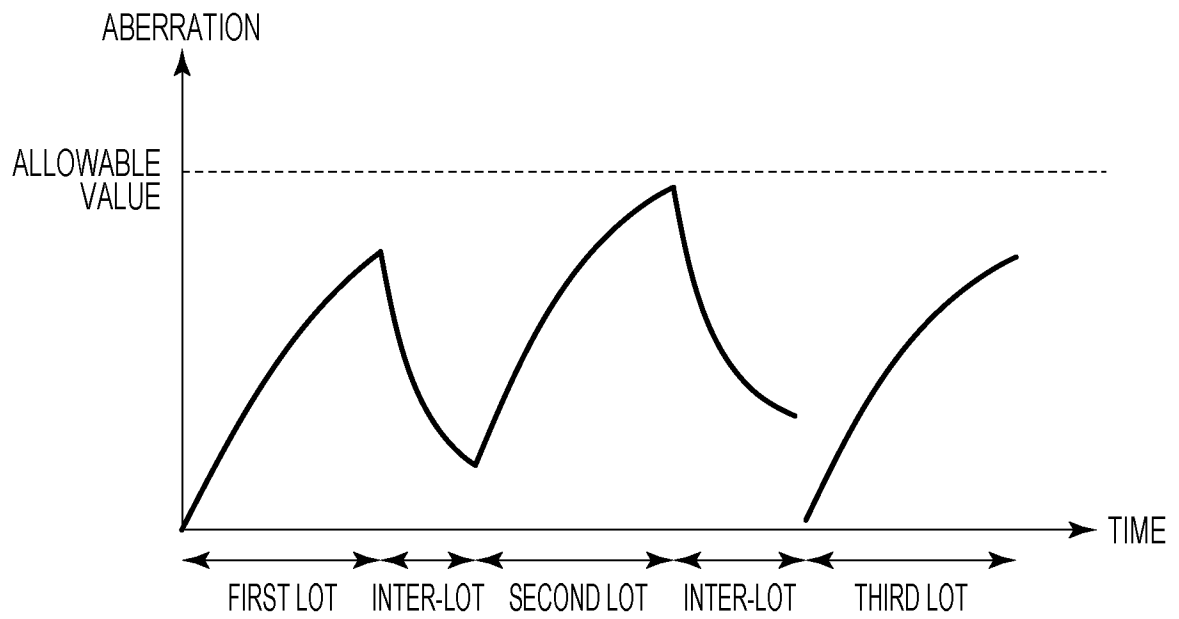


FIG. 6C

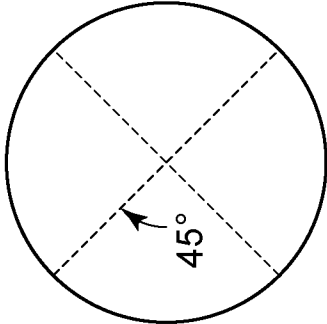
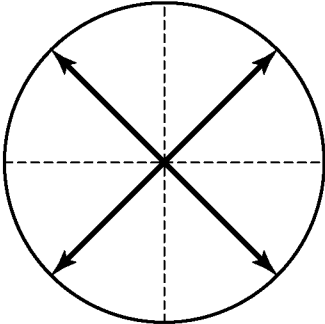
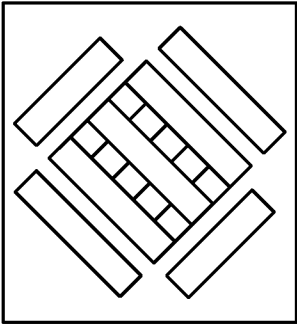


FIG. 6B

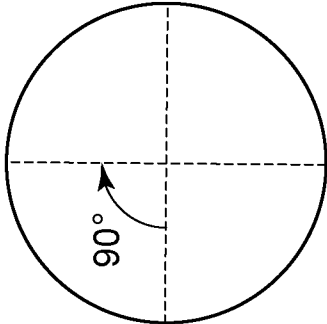
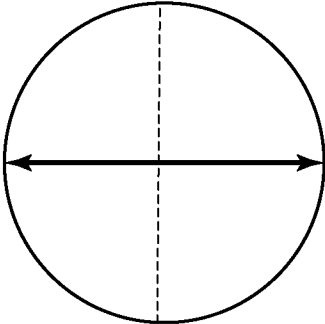
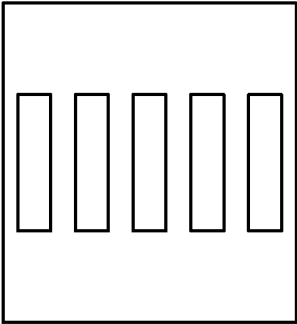
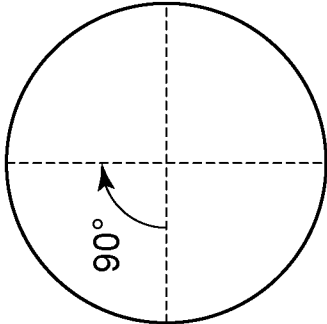
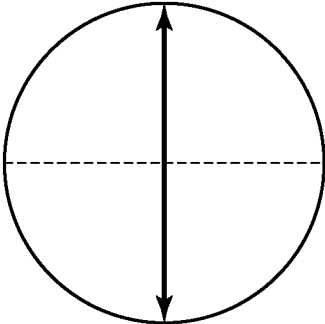
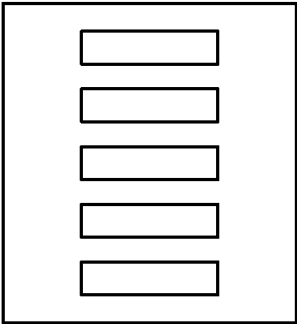


FIG. 6A



MASK PATTERN

ABERRATION GENERATION
DIRECTION IN OPTICAL
ELEMENT

ROTATIONAL ANGLE
OF MASK

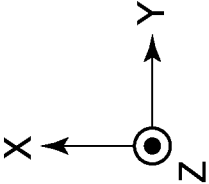


FIG. 7

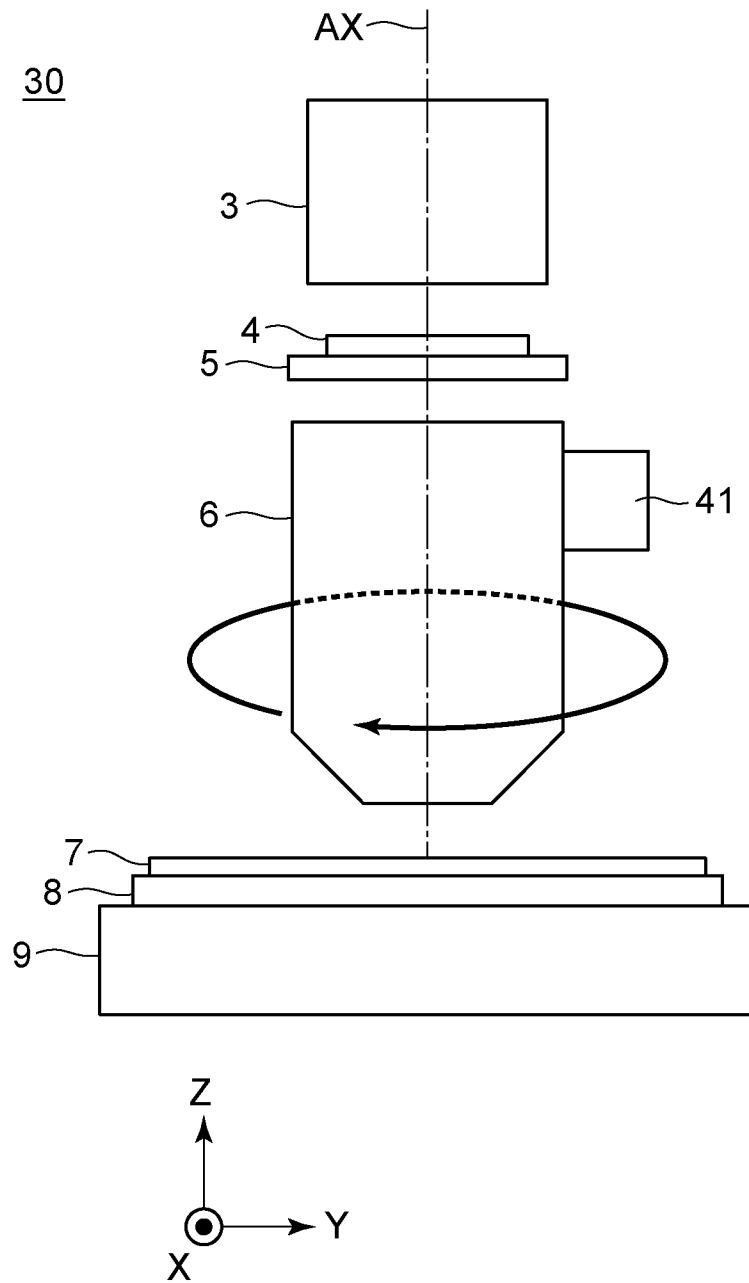


FIG. 8

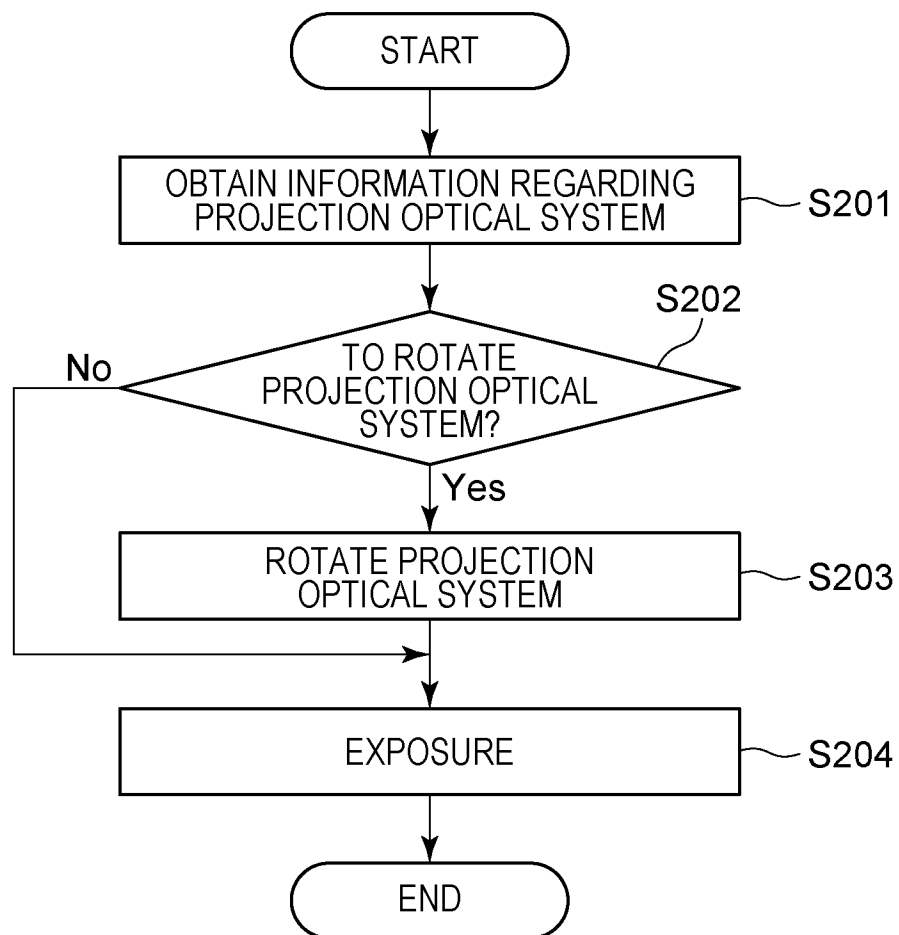


FIG. 9

30

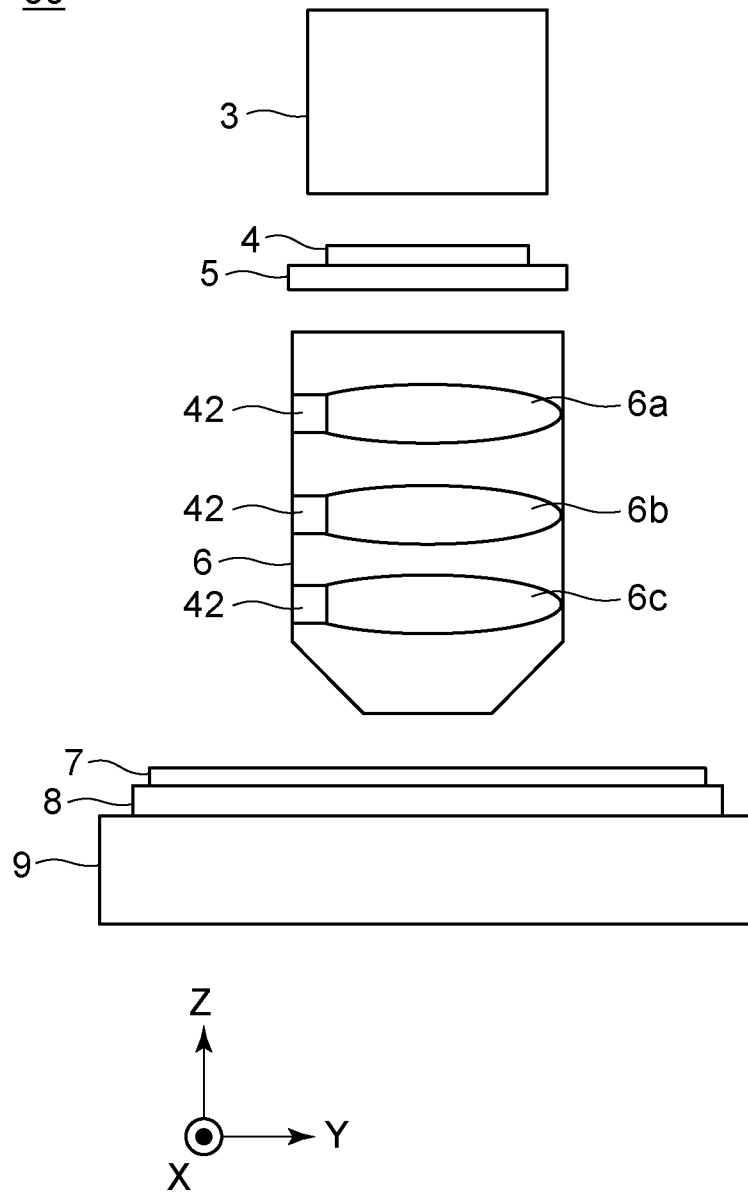


FIG. 10

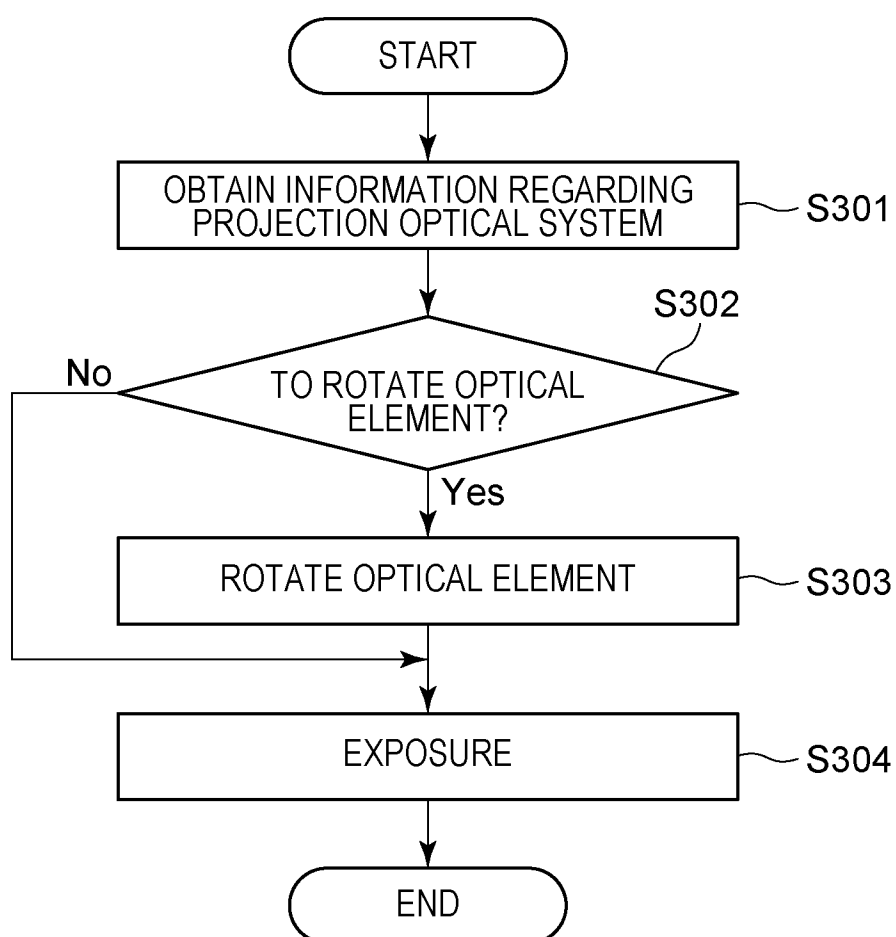


FIG. 11

